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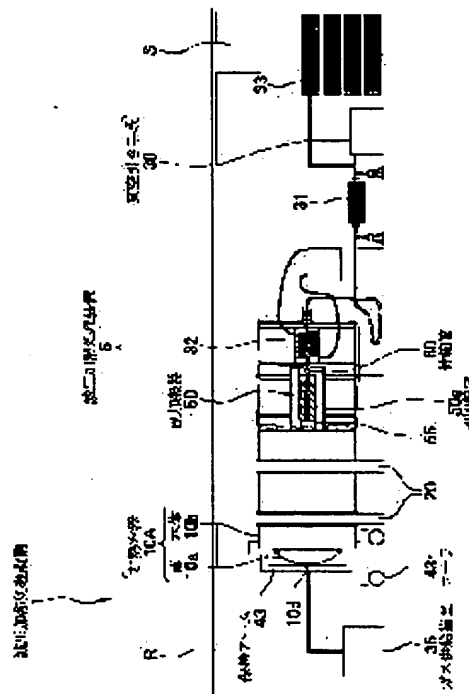
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(54) VACUUM HEAT TREATMENT APPARATUS FOR ENVIRONMENTALLY HARMFUL ORGANIC CHEMICAL SUBSTANCE RESIDUE AND ACTIVATED CARBON MANUFACTURING METHOD USING VACUUM HEAT TREATMENT APPARATUS

(57)Abstract:

PROBLEM TO BE SOLVED: To provide an efficient vacuum heat treatment apparatus for an environmentally harmful organic chemical substance residue, capable of surely, decomposing the organic chemical substance in exhaust gas generated by decomposing the environmentally harmful organic chemical substance residue and easily feeding the residue into the vacuum heat treatment apparatus, and an activated carbon manufacturing method using the vacuum heat treatment apparatus.

SOLUTION: The treatment apparatus for thermally decomposing matter to be treated containing the environmentally harmful residual organic chemical substance consists of a heating container 10 equipped with an airtight heating chamber for heating the matter to be treated housed in the treatment apparatus, an evacuating means 30 for



evacuating the heating chamber and a heating means for raising the temperature in the heating chamber to 650°C or higher to hold the same to 650°C or higher. The heating means is a heater 15 and the heater 15 is arranged in the heating chamber of the heating container 10.

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